

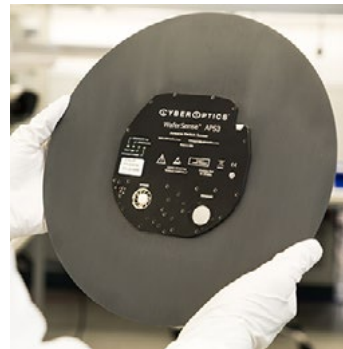
MEASUREMENT ON TEL CLEAN TRACK & LITHIUS TOOLS WITH WAFERSENSE



ATS Auto Teaching Sensor
a wafer to assure proper alignment at TEL Track



AMS200 multi-wafer
with leveling, vibration and humidity is an ideal target for TEL Tracks. Maintaining these track tools requires well calibrated wafer handling as well as the monitoring of humidity in the chambers.



APS2-200 particle sensor
is useful to Track users. TEL Tracks have many chambers and moving parts so identifying particle sources can be difficult using traditional surface scan wafers. However with APS due to the instant partitioning ability, particle sources can be quickly discovered.



Complete package
WaferSense device, USB link, application software, clean charging case with electrical outlet adapter, carrying suitcase, user manual

TEL Track ATS Example

WAFERSENSE™ ATS
ATS viewing a Track target

Track Target (yellow)

ATS Wafer Center (Red)

TV MONITOR
HOLE
GAP PIN
X-axis
Y-axis

Compare to the simple CCD Interface

- Capture "before" & "after" data
- X & Y offsets instantly reported by ATS for fast & accurate handoff teaching
- accurate to 100um

Solutions also for:
CVD, PVD, ALD, Wet & Dry Etch, Plasma Etch, Litho, Ion Implant, FOUPs, EFEM, Diffusion, Test & Inspection, RTA, RTP, Thermal oxidation / metallization, CMP, Metrology, Micro contamination, Auto handling system